

3D OPTICAL METROLOGY

ContourX-1000 Profilometer

Self-Calibrating, Fully Automated Solution for Research and Production

ContourX-1000 3D Optical Profilometer

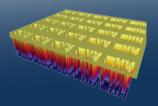
BRUKER

The floor-standing ContourX-1000 white light interferometry (WLI) system incorporates the very latest Bruker hardware and software innovations for fully automated 3D areal measurements of surface texture and roughness. New one-click Advanced Find SurfaceTM with auto-focus and auto-illumination improves user experience and time-to-result, eliminating the need to manually register the surface before each measurement. Combined with its self-adapting measurement mode USI and guided, simplified VisionXpressTM interface, the ContourX-1000 provides uncompromised metrology on any surface, by any operator, even in multi-user high-volume production facilities.

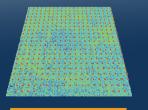
Only the ContourX-1000:

- Provides fast and flexible production-floor metrology with tip/tilt head, dual-light source, and advanced automation
- Ensures extreme accuracy and reliability with selfcalibrating laser and integrated vibration isolation
- Enables most user-friendly measurement and analysis software with guided, simplified routines and recipes





High-aspect-ratio MEMS structure



High-density bump interconnect

Stitched measurement of a bifocal contact lens showing form

Embodying the Power and Versatility of Non-Contact Surface Metrology

Culmination of Latest Optical Profiling Hardware Advances

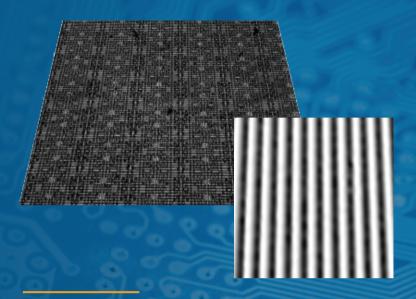
The ContourX-1000 features a combination of Bruker's patented tip/tilt head, proprietary dual-LED light source, automated turret and stages, and selection of wafer chucks. These and other innovations enable rapid optimization for almost any development and production application, including difficult surfaces and deep trenches.

Benchmark for Accuracy and Robustness

In addition to the unmatched measurement and imaging capabilities of Bruker-exclusive interferometry technology, the ContourX-1000 is equipped with a proprietary internal laser reference and integrated vibration isolation for maximum stability and tool-to-tool matching. The system ensures gage-capable metrology performance even in noisy environments.

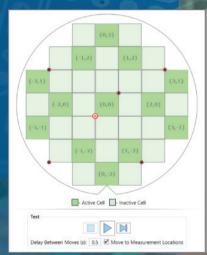
Paragon of Powerful Automated Measurement and Analysis

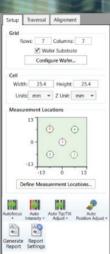
Universal Scanning Interferometry (USI) self-adapting measurement mode automatically determines the optimal measurement parameters to maintain nanometer-level resolution even over a range of tens of microns. The guided, simplified VisionXpress interface decouples analysis quality from operator experience level for fast time to best metrology results. Even in multiuser environments, each user is empowered to obtain quality results with the Advanced Find Surface capability, triggering an auto-focus and auto-illumination adjustment process. With a full suite of compatible software packages, from SureVision and Multi-Region Analysis to Vision64 Map™ and Film Measurement, ContourX-1000 allows for uncompromised metrology to match your specific application.



Background: IC chip topography with overlay of automated optical inspection (AOI) image

Foreground: 1 µm periodic polymer grating





Automation graphical user interface (GUI) with wafer map

ContourX-1000 Specifications

		Service a	
Measurement Modes	PSI, USI, VSI, Optional Film		
Max. Scan Range	≤10 mm	Bruker has a long t with our customer application issues. generation technol leaders and assisti the right system ar partnership contine extended service I sold. Our highly tracof support engineer and subject-matter dedicated to maximus with system service as application support wide range of	
Vertical Resolution ¹	<0.01 nm		
Lateral Resolution	0.38 µm minimum (Sparrow criterion); 0.13 µm (with AcuityXR®)		
Step Height Accuracy ²	<0.75%		
Step Height Repeatability	<0.125% 1 sigma repeatability		
Max. Scan	≤122 µm/sec (with laser reference)		
Sample Reflectivity	0.05% to 100%		
Max. Sample Slope	≤40° (shiny surfaces); ≤87° (rough surfaces)		
Sample Height	≤100 mm		
Sample Weight	≤45 kg		
XY Sample Stage	300 mm automated (0.5 μm encoders); Integrated vibration isolation table		
Z Focusing	100 mm automated		
Tip/Tilt Function	±5° automated in head		
Optical Metrology Module	Patented dual-LED illumination		
Objectives	Parfocal: 2.5X, 5X, 10X, 20X, 50X, 100X, 115X; LWD: 1X, 2X, 5X, 10X; TTM: 2X, 5X, 10X, 20X; Bright Field: 2.5X, 5X, 10X, 50X Single-objective adapter; Optional motorized five-position turret		
Available Zoom Lenses	0.55X, 0.75X, 1X 1.5X, 2X auto-sensing modules		

5 MP monochrome with 1200 x 1000 data array; Optional color camera

On-fly analysis; Scattered and grid automation; Recording in database Via NIST/PTB traceable step height and lateral ruler standards;

AcuityXR; Advanced PSI; Automatic Pattern Alignment; MATLAB; Multiple Region Analysis;

English; German; French; Italian; Spanish; Japanese; Chinese; Polish; Korean; Brazilian Portuguese; Russian

Optical Microlens Analysis; Production Mode; SDK; TCP/IP; SureVision; Vision64 Map

Vision64® and VisionXpress on Windows 10 LTS 64-bit OS

Auto-focus; Auto-intensity; Auto-saving; Auto-stitching;

Optional auto and continuous internal laser signal

852 mm x 793 mm x 1608 mm (W x D x H)

Bruker's Industry-Best nd Support

tradition of partnering rs to solve real-world After developing nextologies with industry ing customers in selecting nd accessories, this nues through training and long after the tools are ained and certified team ers, application scientists, er experts are wholly imizing your productivity ice and upgrades, as well port and training across a f disciplines.

493 kg

12 months

Bruker Nano Surfaces and Metrology

San Jose, CA • USA Phone +1.866.262.4040

Camera

Software System

Software Packages

Reporting Languages

Automation

Calibration

Weight

Warranty

Certification

System Footprint

productinfo@bruker.com

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www.bruker.com/ContourX-1000

CE-Certification: ANSI B46.1 compliant ¹As demonstrated by taking the one sigma Sq value of 30 PSI repeatability measurements on an SiC reference mirror.

² Absolute accuracy for step heights 8 µm and higher